POLYTEKNIK
When thin film matters



PVD SYSTEMS

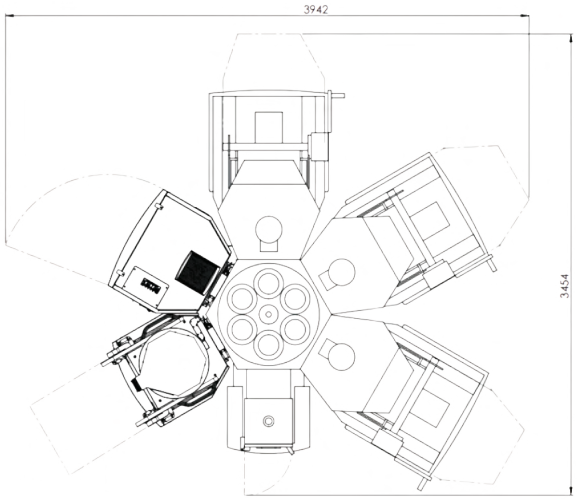
Flextura® Cluster

The modular cluster platform for 200 mm and 300 mm wafers. Start with the processes you need today and add modules as your capacity or process needs grow

Flextura®
200 Cluster

The Flextura® Cluster platform is probably the most flexible 200mm cluster tool available. It is truly almost Plug&Play and you may add process modules as your need for capacity or new processes increase.





Driven by unique processes

- CSM sputtering (DC, RF, pDC, and HiPIMS)
- Multi magnetron chamber (co-sputtering)
- Automated glancing angle deposition on 200mm wafers
- E-beam evaporation
- Remote Plasma Sputtering technology
- RF/ICP etch, degas, cooling, alignment
- Single wafer or batch processing directly from cassette-to-cassette

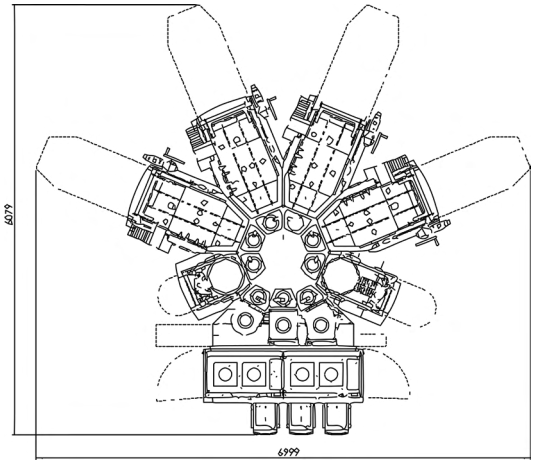
FLEXIBILITY AND RELIABILITY IS KEY

Scalable capacity from medium to high volume production	Fully modularised platform – from single chamber to cluster	Fully automated process control with advanced data logging	SECS/GEM, MES integration optional
Strong reliable 24/7 production tools	Up to 200mm wafers	Combinations of sputtering and e-beam	CMOS compatible

Flextura®
300 Cluster

The Flextura® 300 Cluster tool – a highly reliable PVD platform – is an excellent choice for the deposition of metals, oxides, and nitrides to produce high-quality thin films. Including degas, pre-clean, and PVD modules, and utilising the flexibility of the Flextura® platform, the Flextura® 300 Cluster allows the configuration to be optimised to best fit the application.





Process modules

- CSM sputtering (HiPIMS, RF, and pDC)
- Linear magnetron sputtering
- Multi magnetron chamber (co-sputtering)
- RF/ICP pre-clean
- Degas, cooling, alignment, buffer station
- Evaporation modules
- Glancing angle deposition

PLATFORM HIGHLIGHTS

Atmospheric front-end with Brooks JCP EFEM

Up to four Vision™ Leap load ports supporting 300mm FOUP loading

Substrate heating up to 950°C

Wafer aligner, wafer mapping, cross-slot detection

Transfer module with proven reliable wafer handling by Brooks Magnatran LEAP dual arm robot for maximum throughput and reliability

Up to 6 process modules

GEM300 compliant communication

CMOS compatibility



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Who we are

Polyteknik AS is a PVD equipment manufacturer with an innovative, modular system design and a strong focus on service. With more than 30 years in business, an international reference list and an excellent technology platform, Polyteknik AS has become a valued partner in the thin film industry.

What we do

Our portfolio of PVD systems ranges from small-scale R&D to high-volume and large-area deposition.
The modular Flextura® platform lets you start with the processes your research needs today and add modules, as your projects change. Our Flextura® 200 and 300 Cluster, Tornado and Infinity platforms cover the range from compact research systems to production.
At Polyteknik AS you will meet a dedicated team that works closely with you to find the right solution.

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